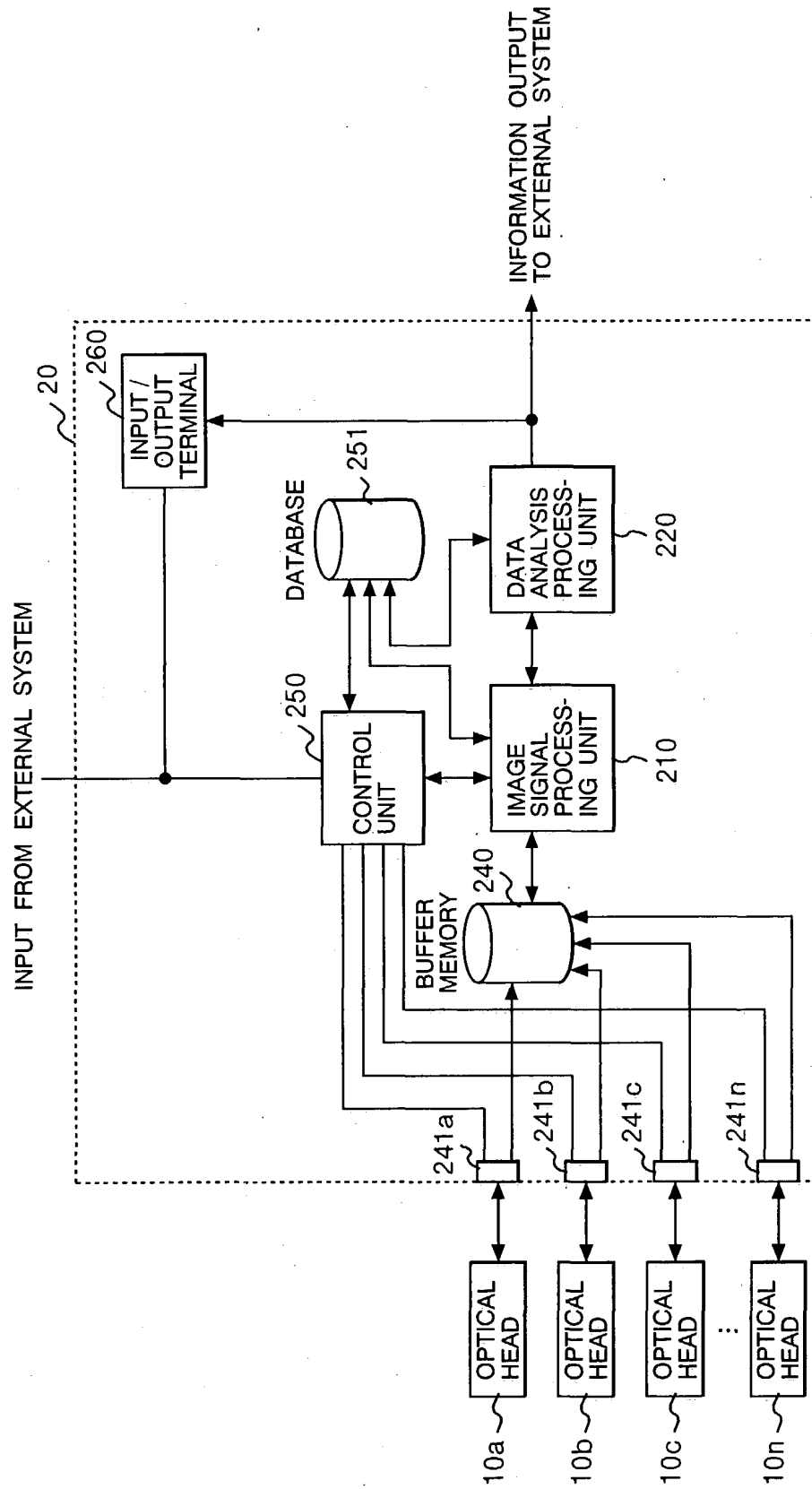
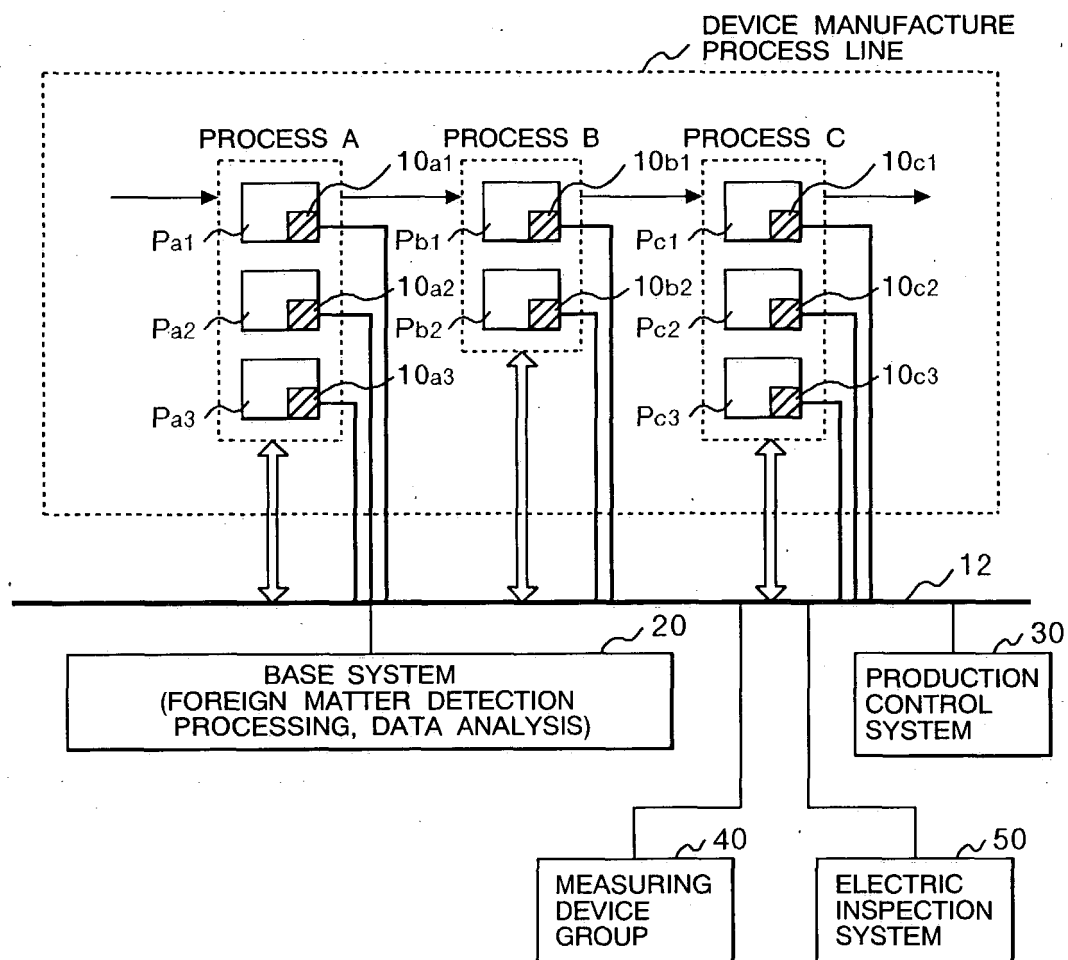
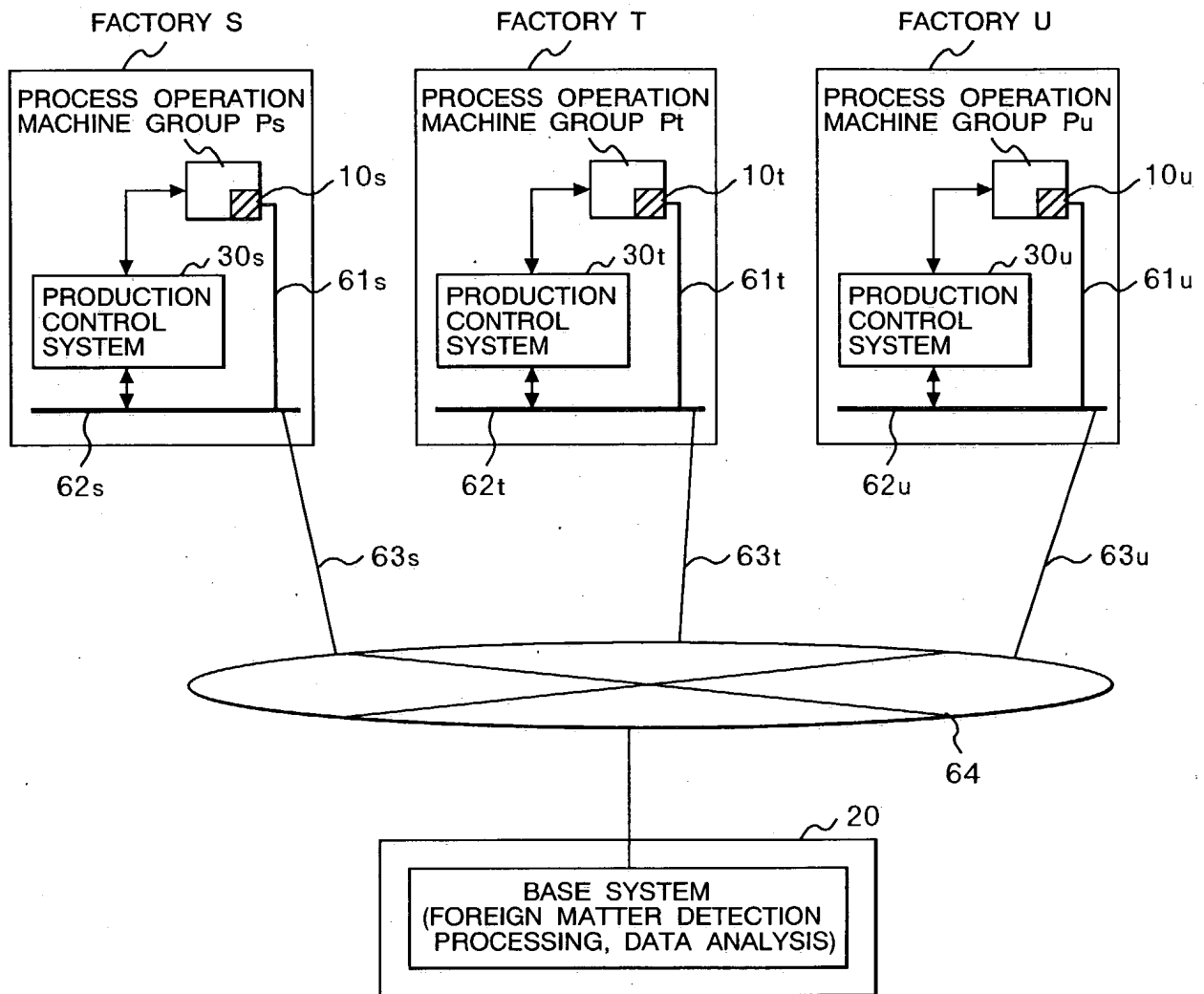
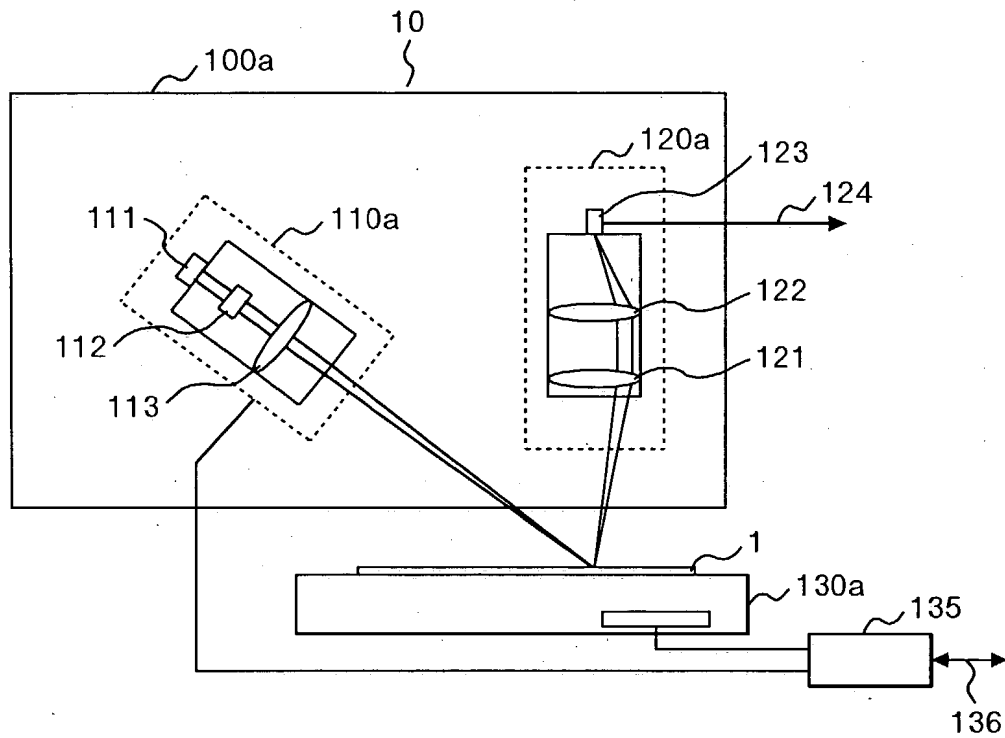
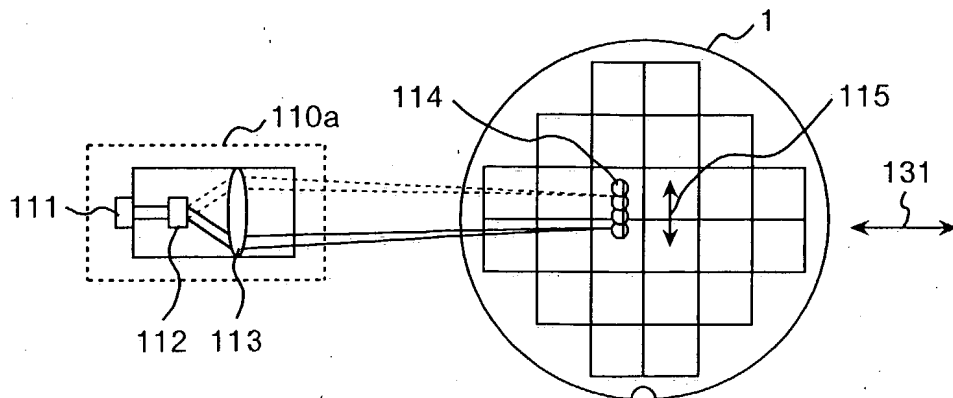


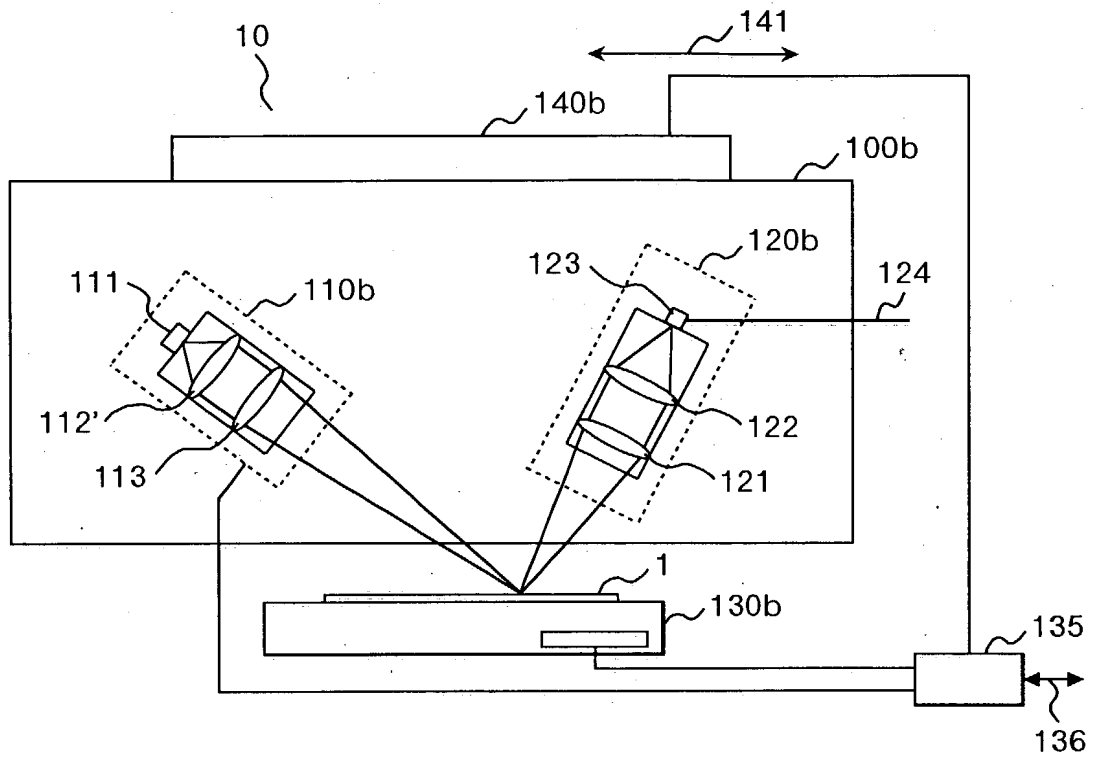
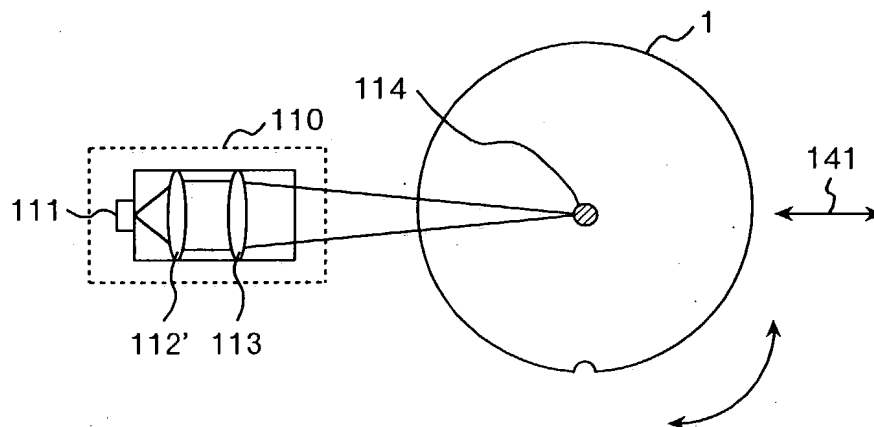
FIG. 1

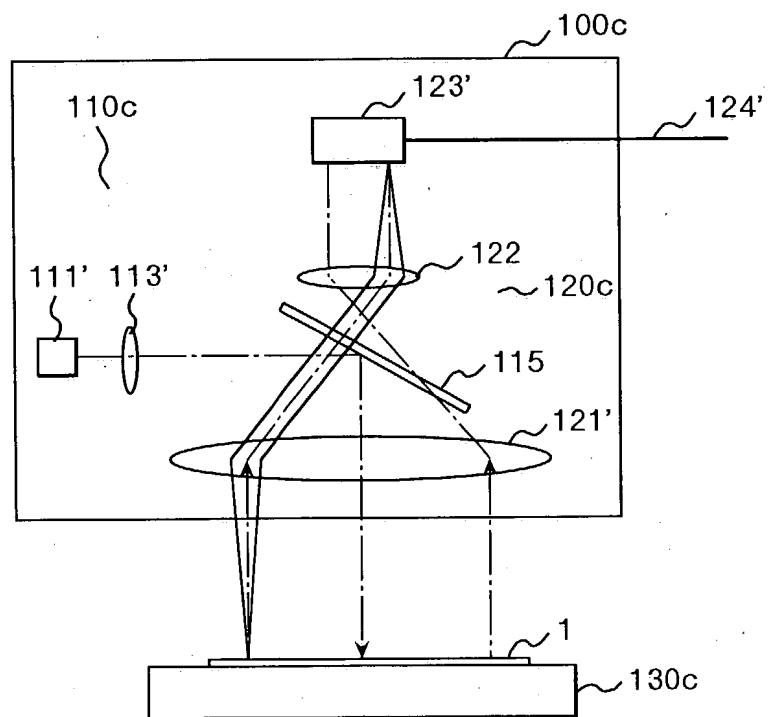


**FIG. 2**

**FIG. 3**

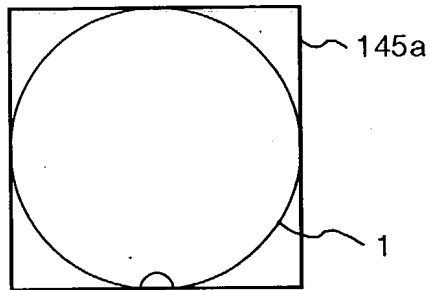
**FIG. 4****FIG. 5**

**FIG. 6****FIG. 7**

**FIG. 8**

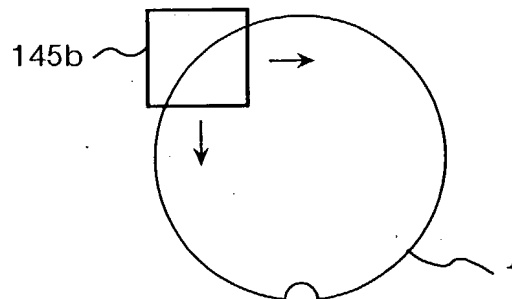
**FIG. 9a**

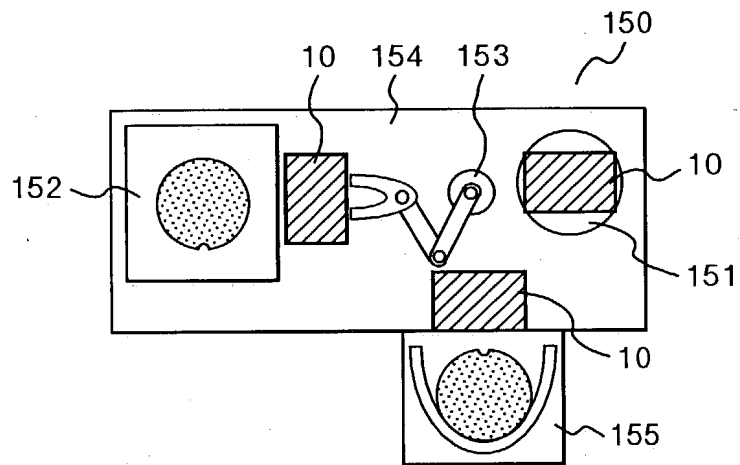
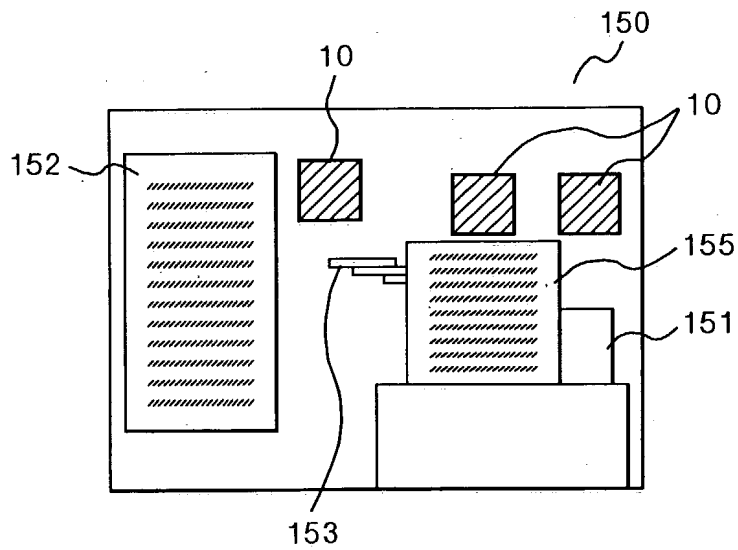
WHOLE WAFER SURFACE INSPECTION



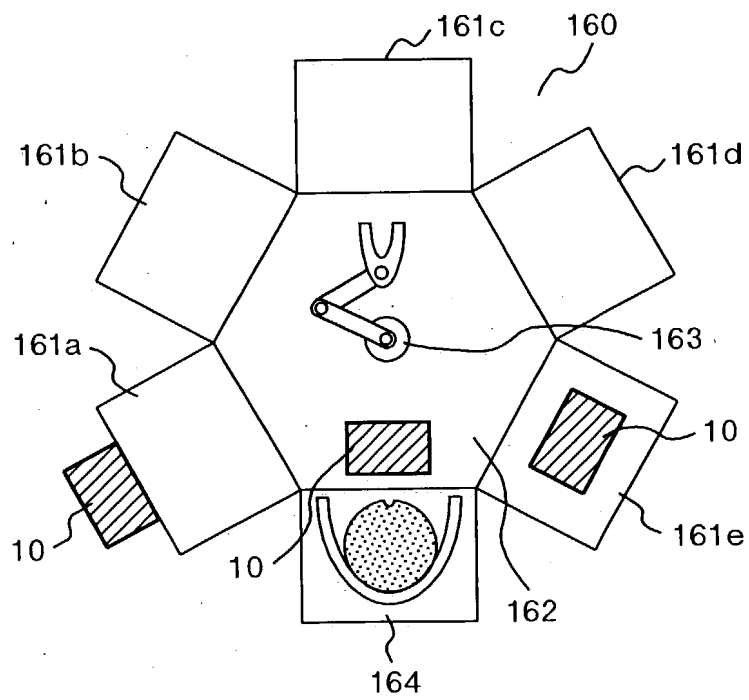
**FIG. 9b**

PIXEL SIZE REDUCED

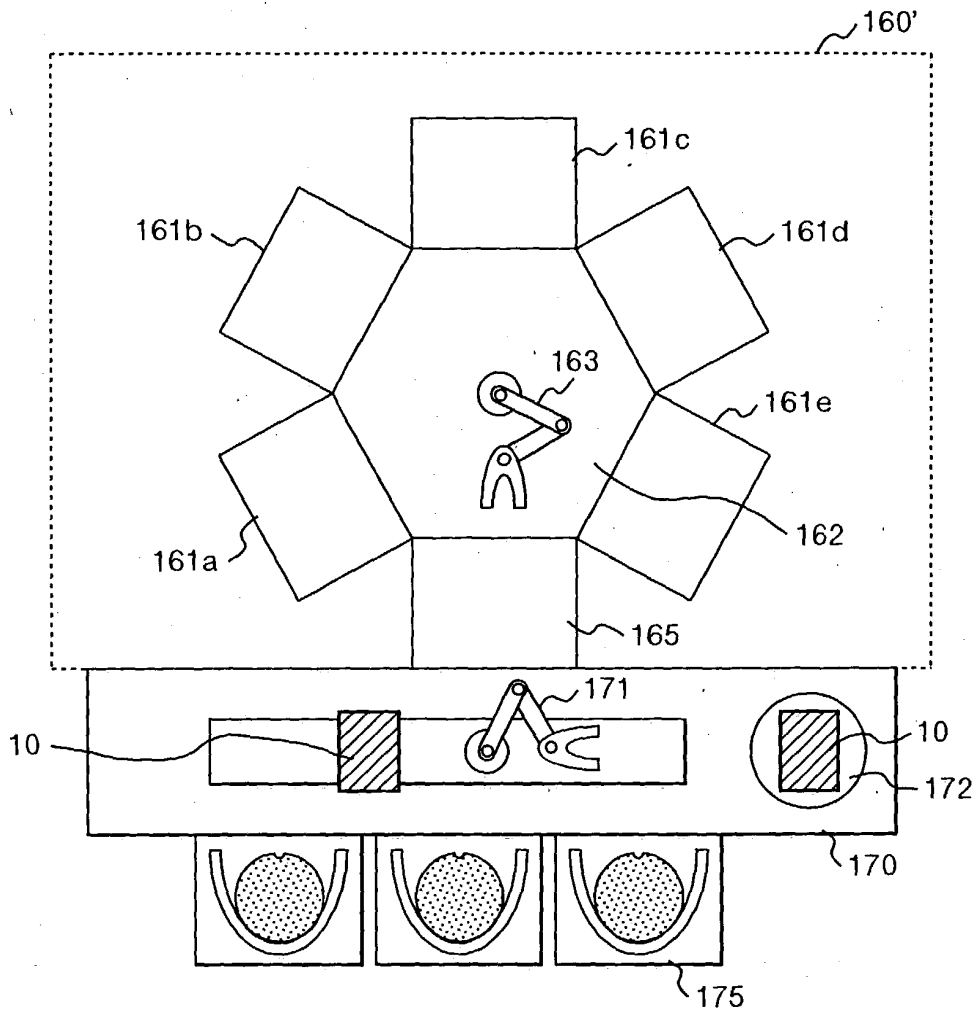


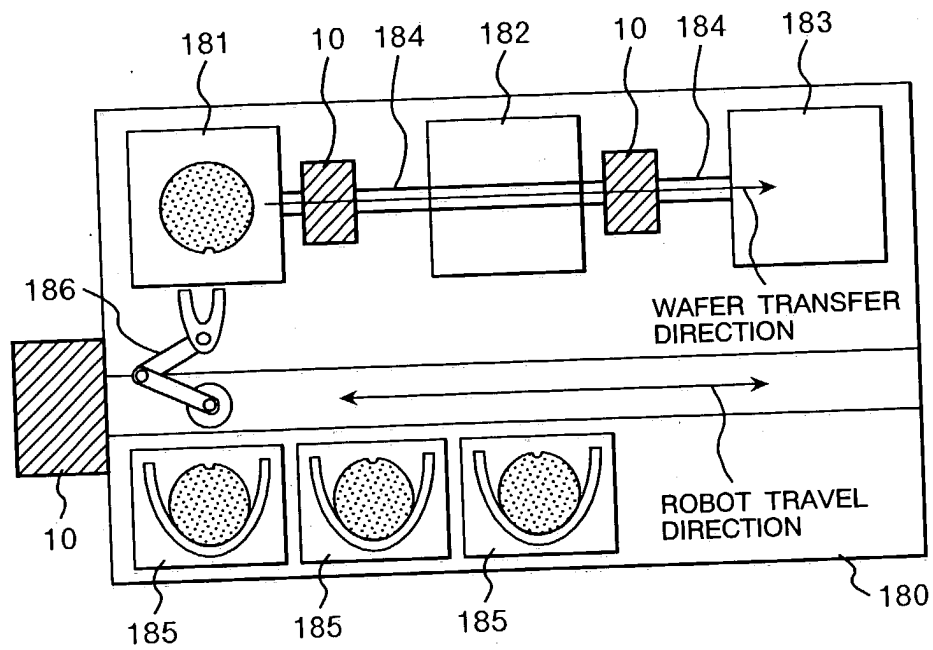
**FIG. 10a****FIG. 10b**



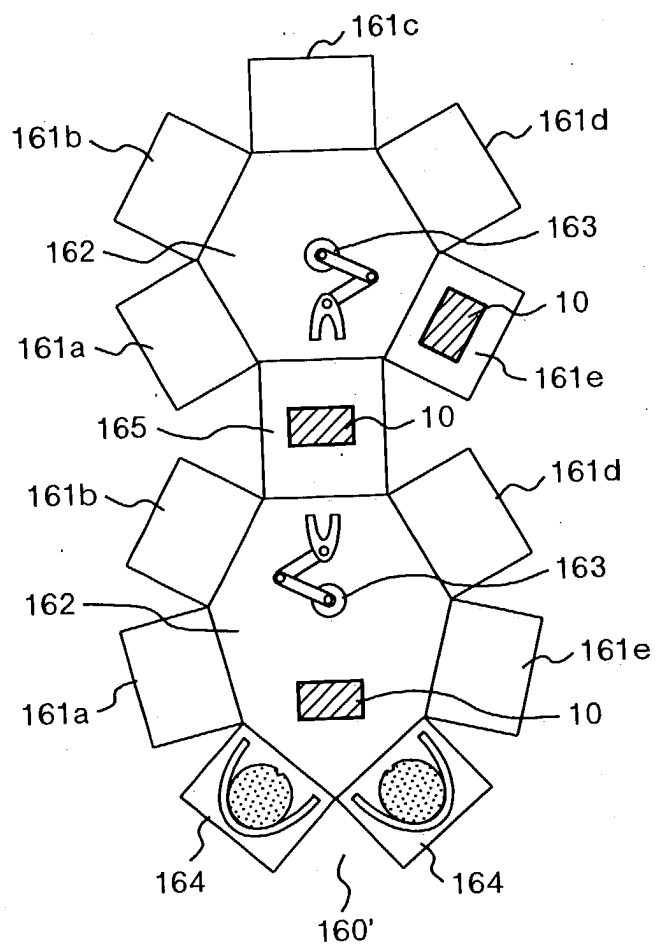
**FIG. 11**

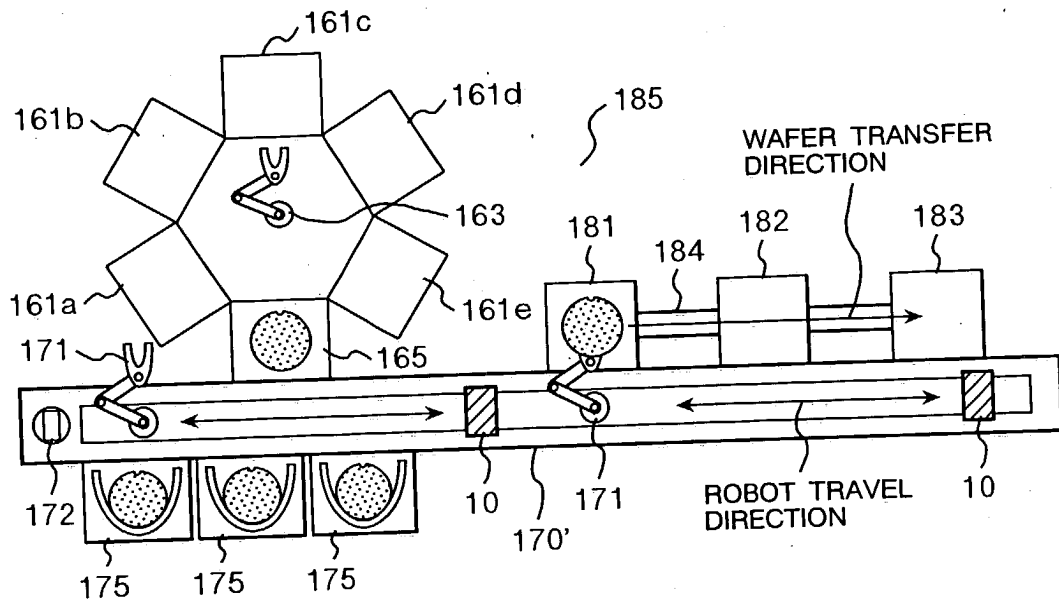
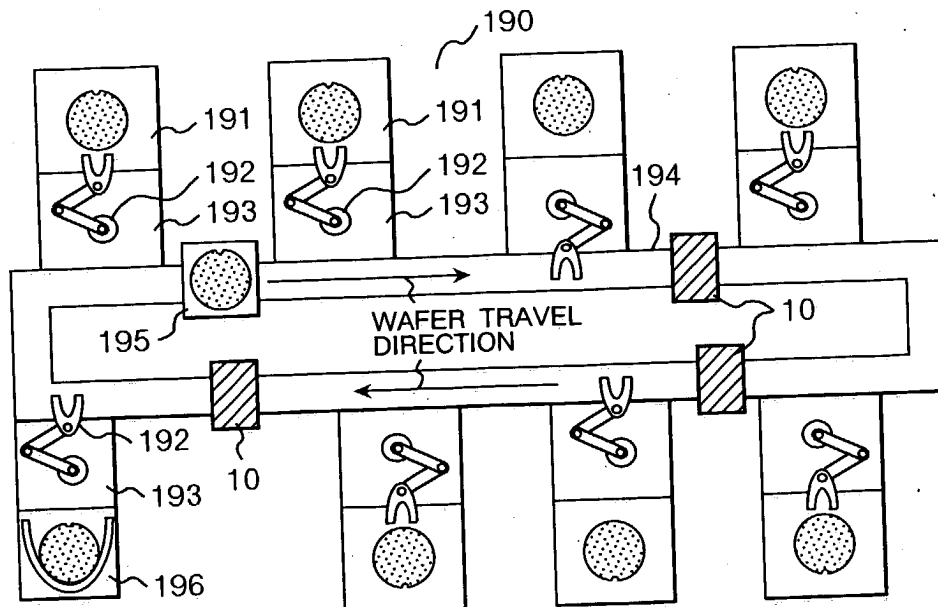
**FIG. 12**

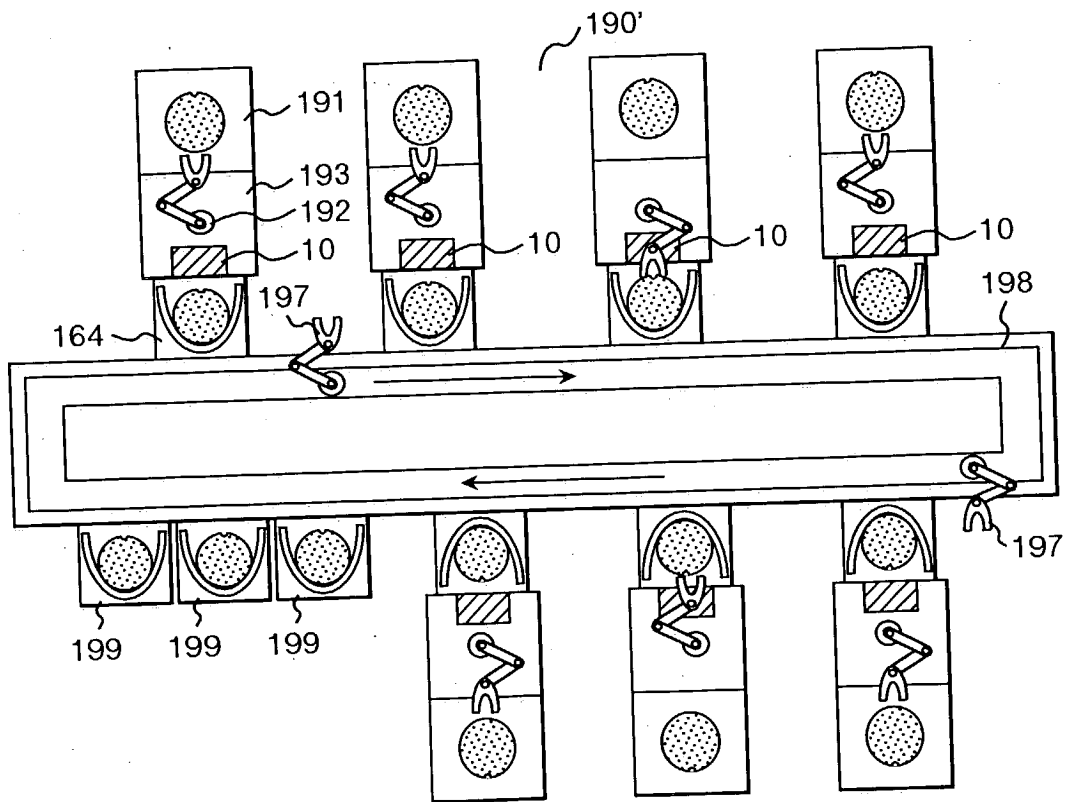


**FIG. 13**

**FIG. 14**



**FIG. 15****FIG. 16**

**FIG. 17**

## FIG. 18

251

- (a) WAFER PROCESS DATA
- (b) LAYOUT DATA ON WAFER
- (c) INSPECTION REQUIREMENTS DATA ON PRODUCTION APPARATUS AND COMPACT FOREIGN MATTER MONITOR
- (d) INSPECTION REFERENCE IMAGE DATA ~ 216
- (e) INSPECTION RECIPE DATA  
 ((e-1) THRESHOLD FOR JUDGMENT, (e-2) QUANTITY OF ILLUMINATION LIGHT, (e-3) INSPECTION AREA, (e-4) INSPECTION METHOD (XY SCAN, ROTARY SCAN), ETC.)
- (f) INSPECTION RESULT DATA
- (g) DEFECTIVE AREA IMAGE DATA
- (h) FAILURE ANALYSIS REFERENCE DATA  
 (FOREIGN MATTER DISTRIBUTION DATA)

## FIG. 19

250

- ① COMPACT FOREIGN MATTER MONITOR (OPTICAL HEAD) ON / OFF MONITOR FUNCTION
- ② SIGNAL PROCESSING TIMING CONTROL (INPUT / OUTPUT CONTROL) FUNCTION
- ③ INSPECTION RECIPE PREPARE FUNCTION
- ④ IDENTIFICATION CODE RECOGNIZE FUNCTION
- ⑤ INSPECTION RECIPE SELECT FUNCTION
- ⑥ ALARM OUTPUT FUNCTION
- ⑦ COMPACT FOREIGN MATTER MONITOR OPTICAL HEAD MAINTENANCE MANAGEMENT FUNCTION  
 (FOR EXAMPLE, REPLACEMENT MANAGEMENT OF LIGHT SOURCE EVERY n WAFERS INSPECTED)

FIG. 20

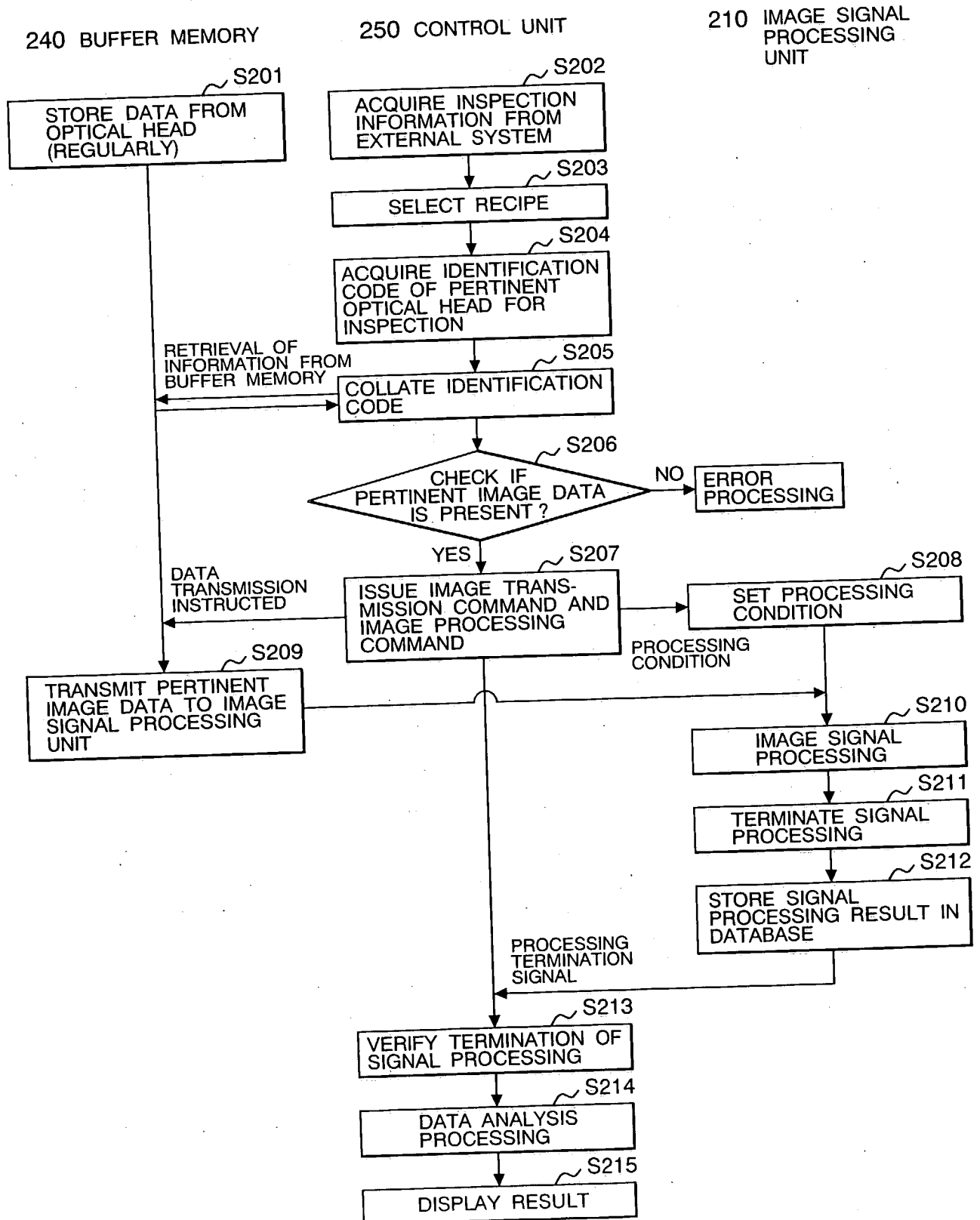
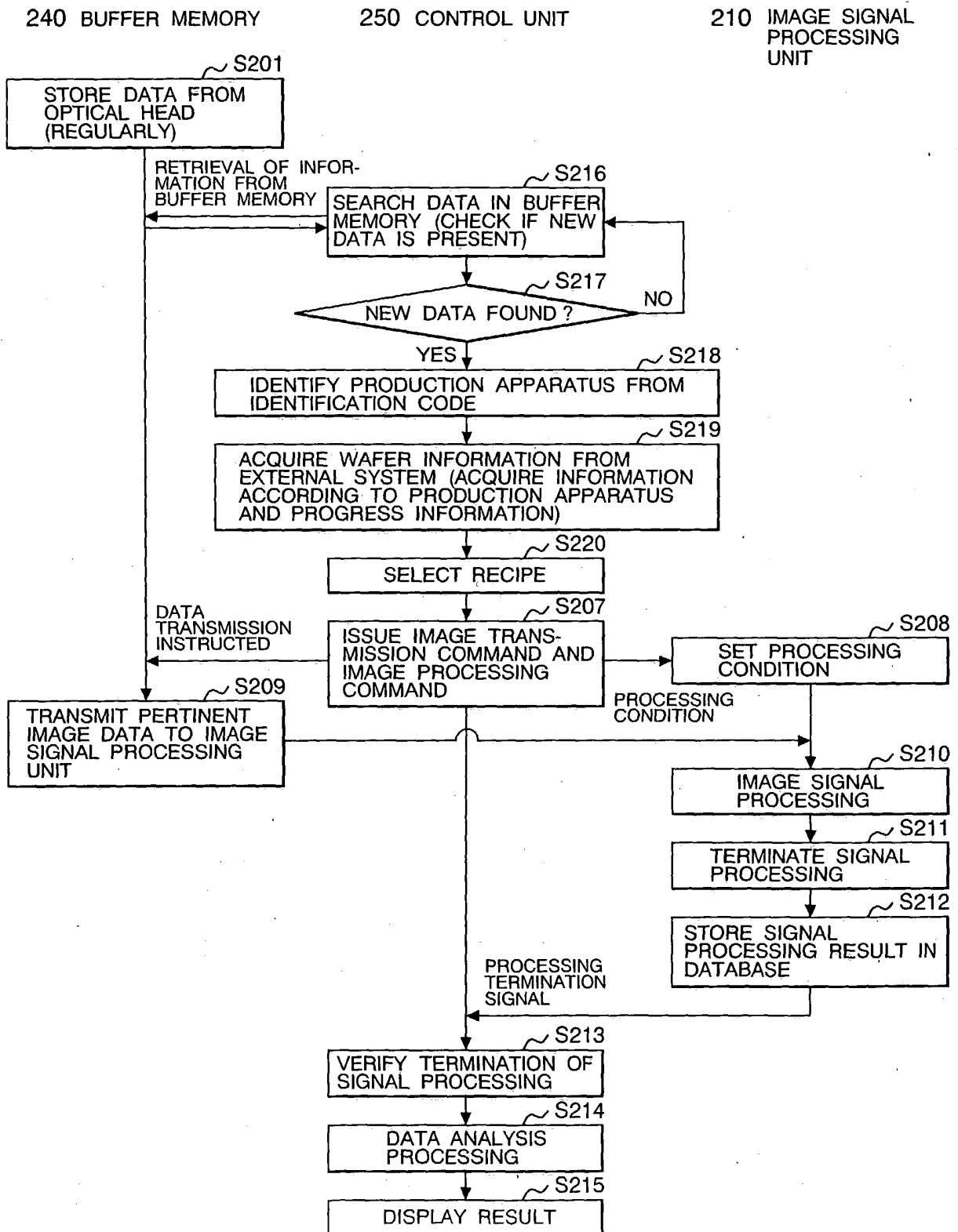
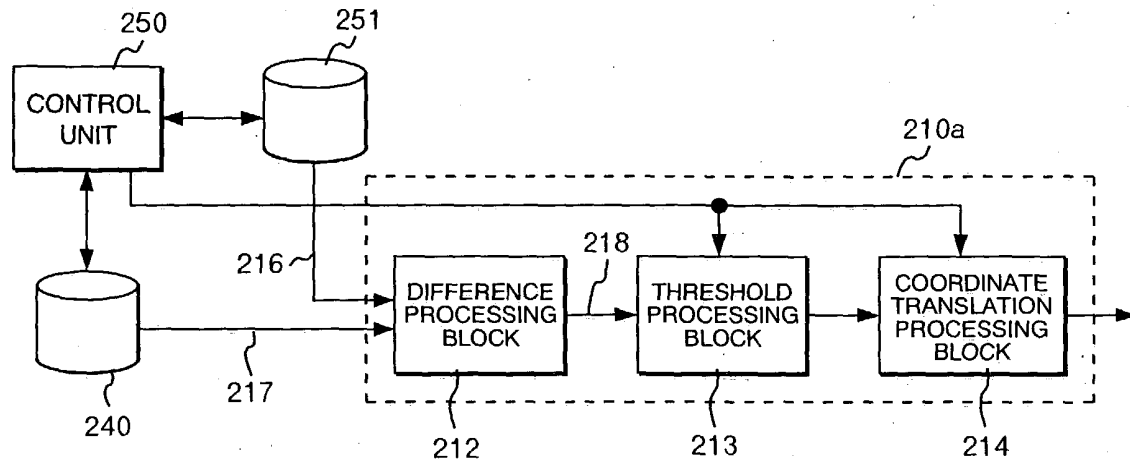
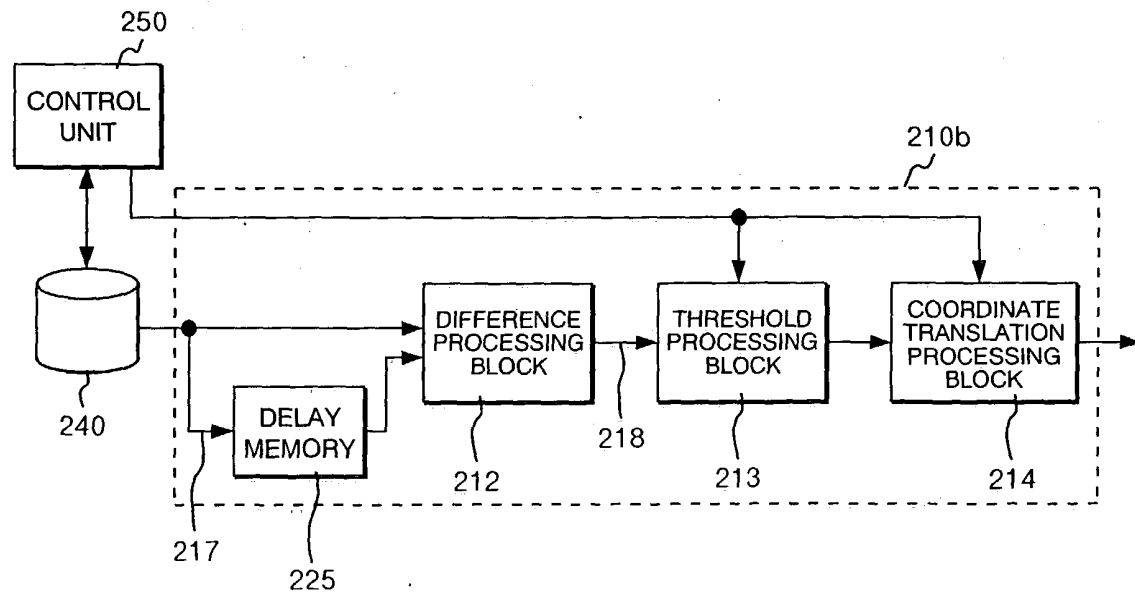
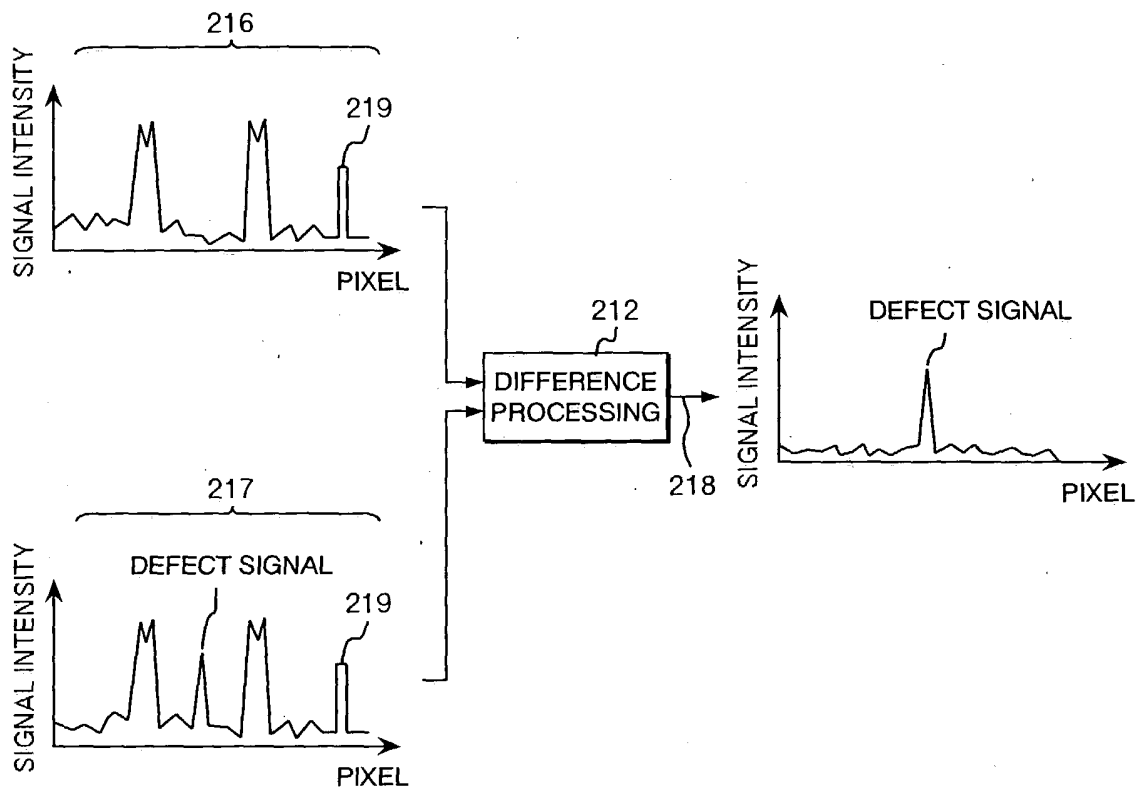


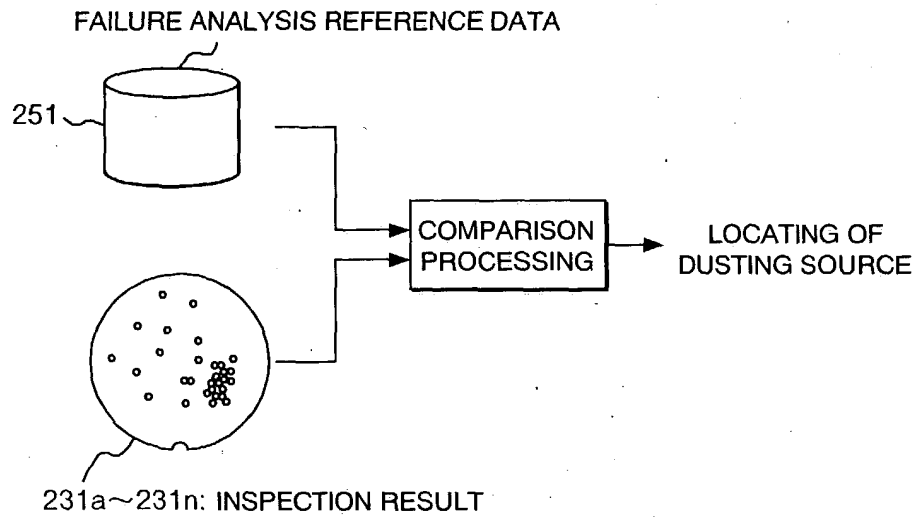
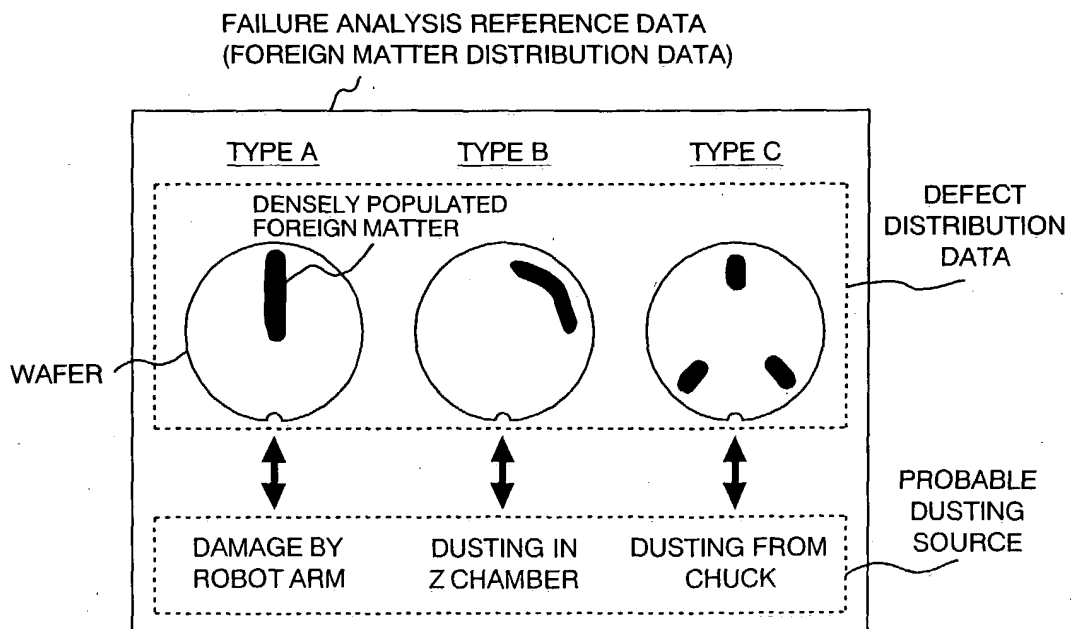


FIG. 21



**FIG. 22****FIG. 23**

**FIG. 24**

**FIG. 25****FIG. 26**

**FIG. 27**

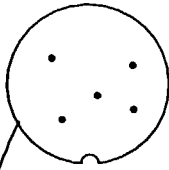
JUDGE BY  
INSPECTION RESULT

EQUIPMENT NAME :   LOT NO. :

PRODUCT NAME :

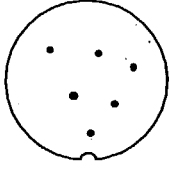
PROCESS NAME :

Status: OCCURRENCE OF  
ABNORMALITY  
(DAMAGE BY ARM) 271

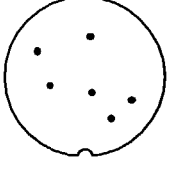


SLOT : 1

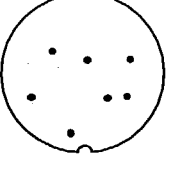
INSPECTION  
RESULT



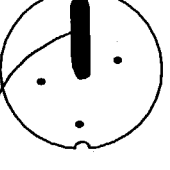
SLOT : 2



SLOT : 3



SLOT : 4



SLOT : 5

INSPECTION RESULT  
OF DEFECTIVE WAFER

SLOT : 6

SLOT : 7

SLOT : 8

SLOT : 9

SLOT : 10

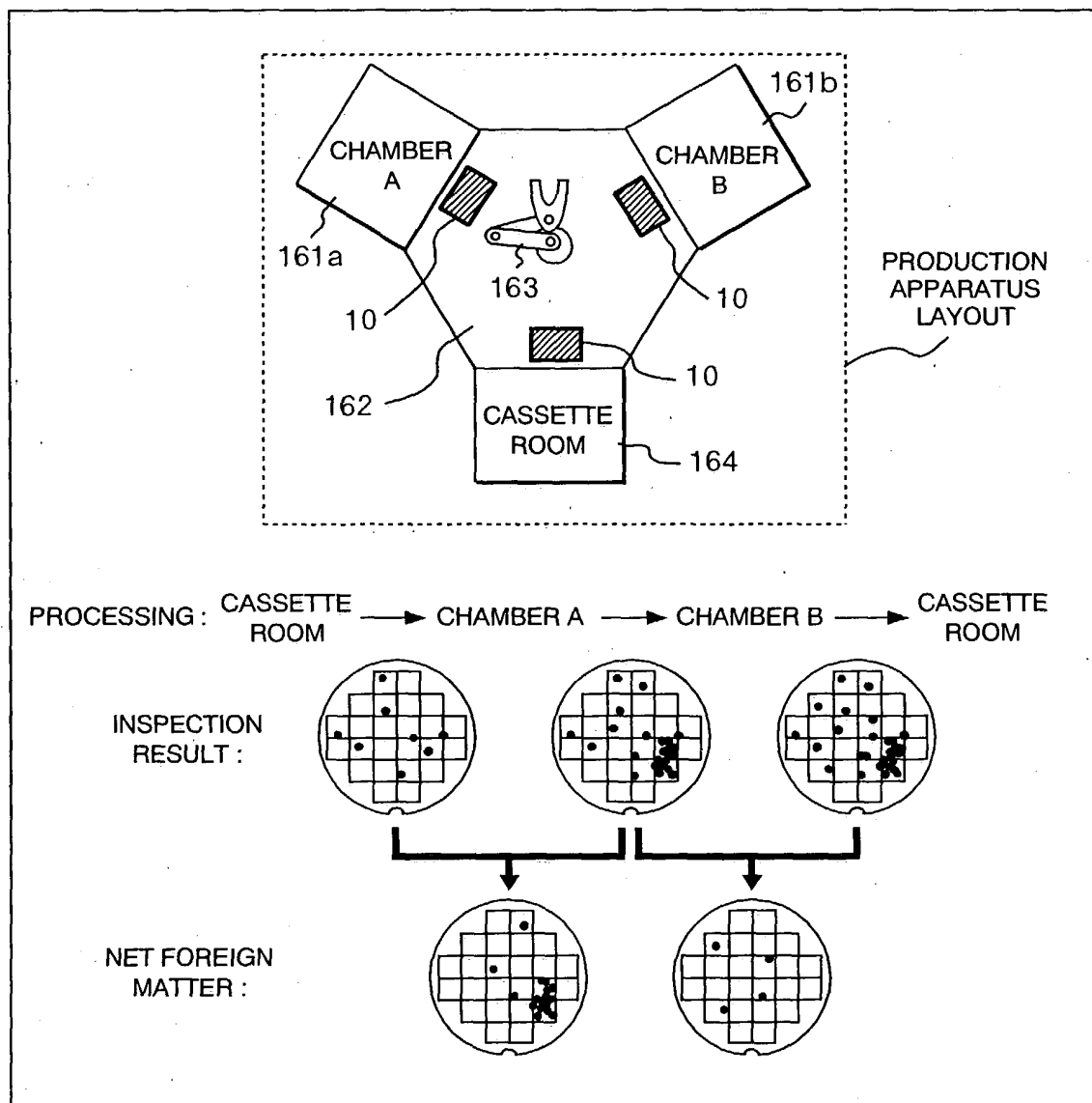
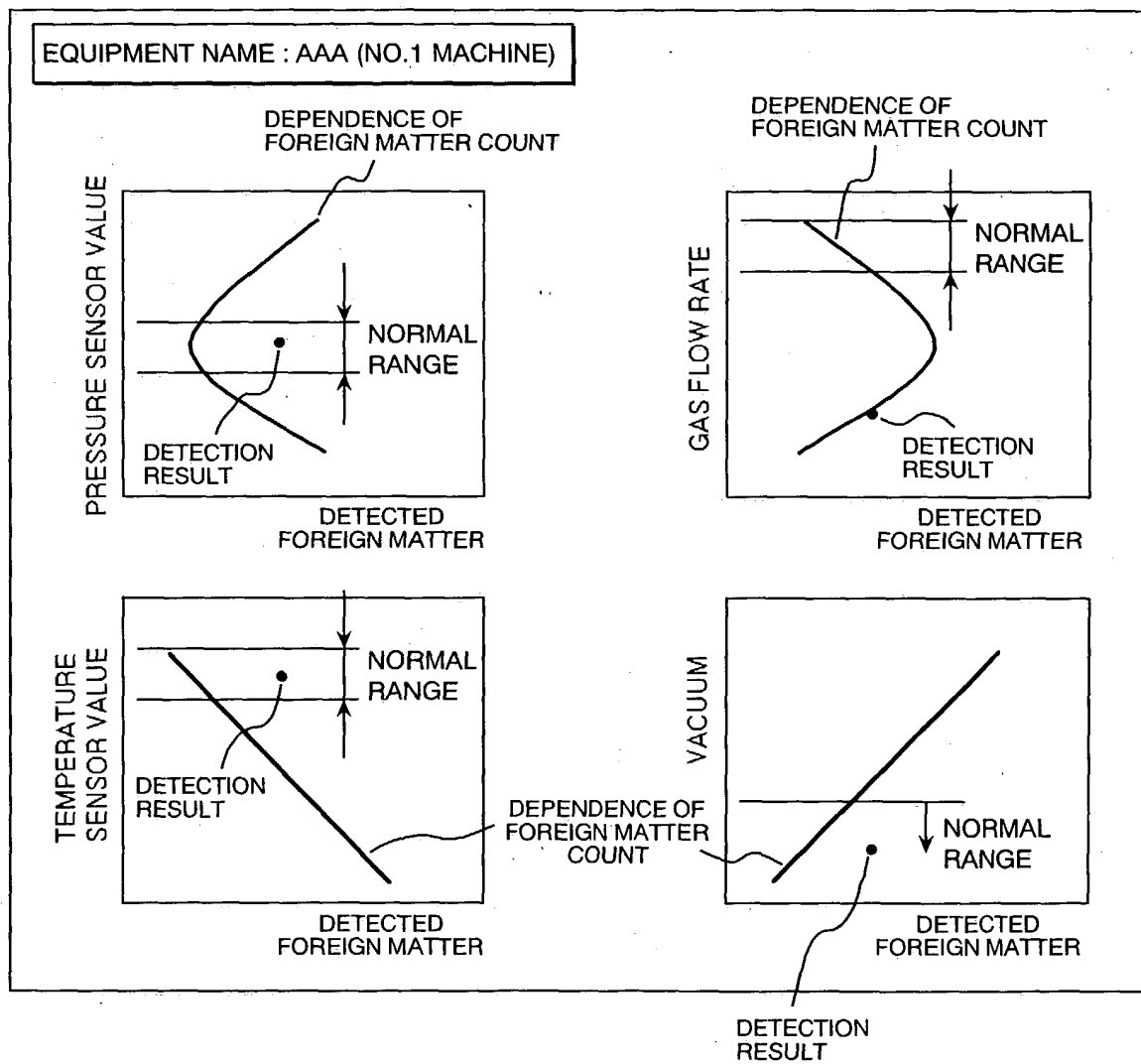
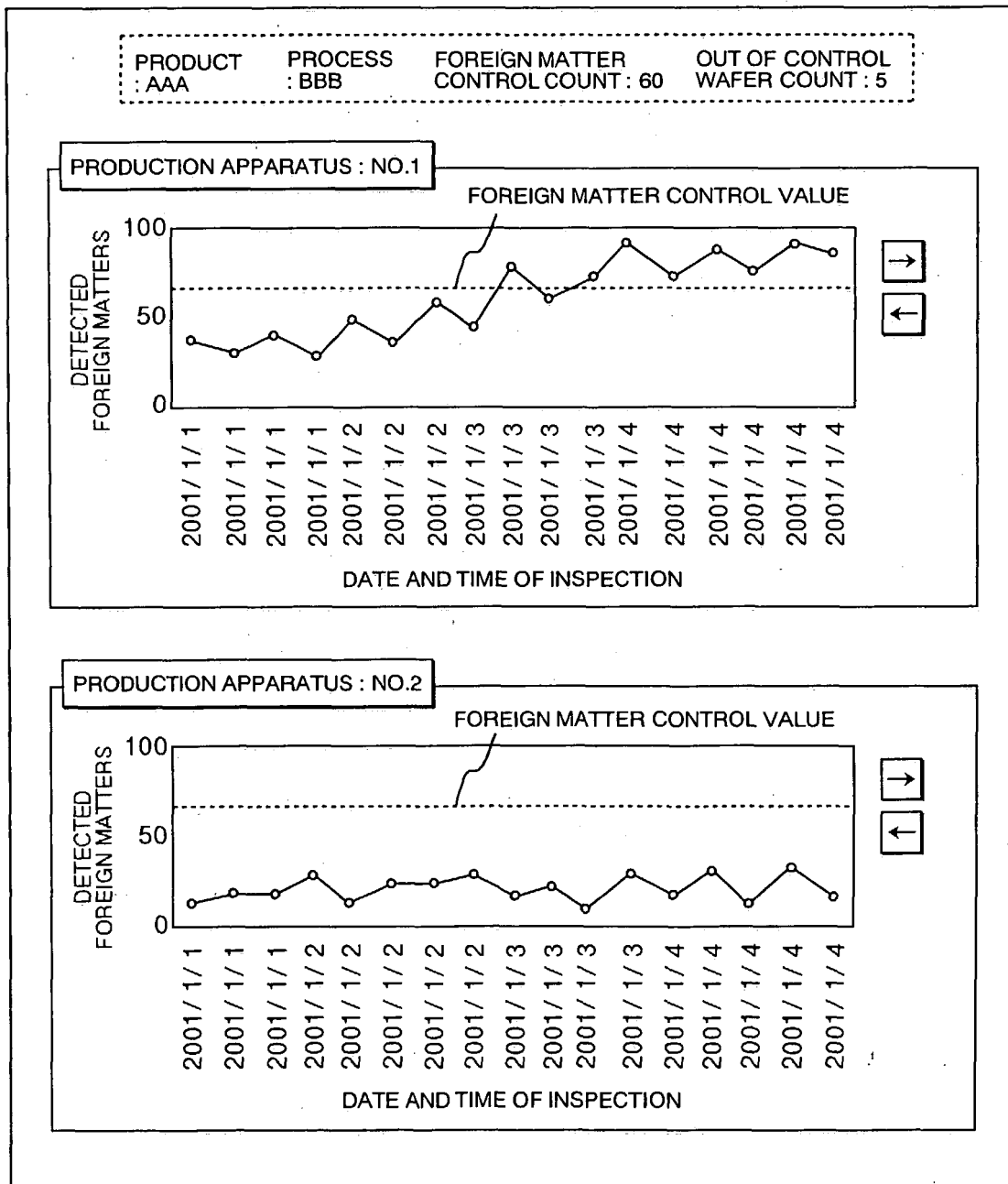
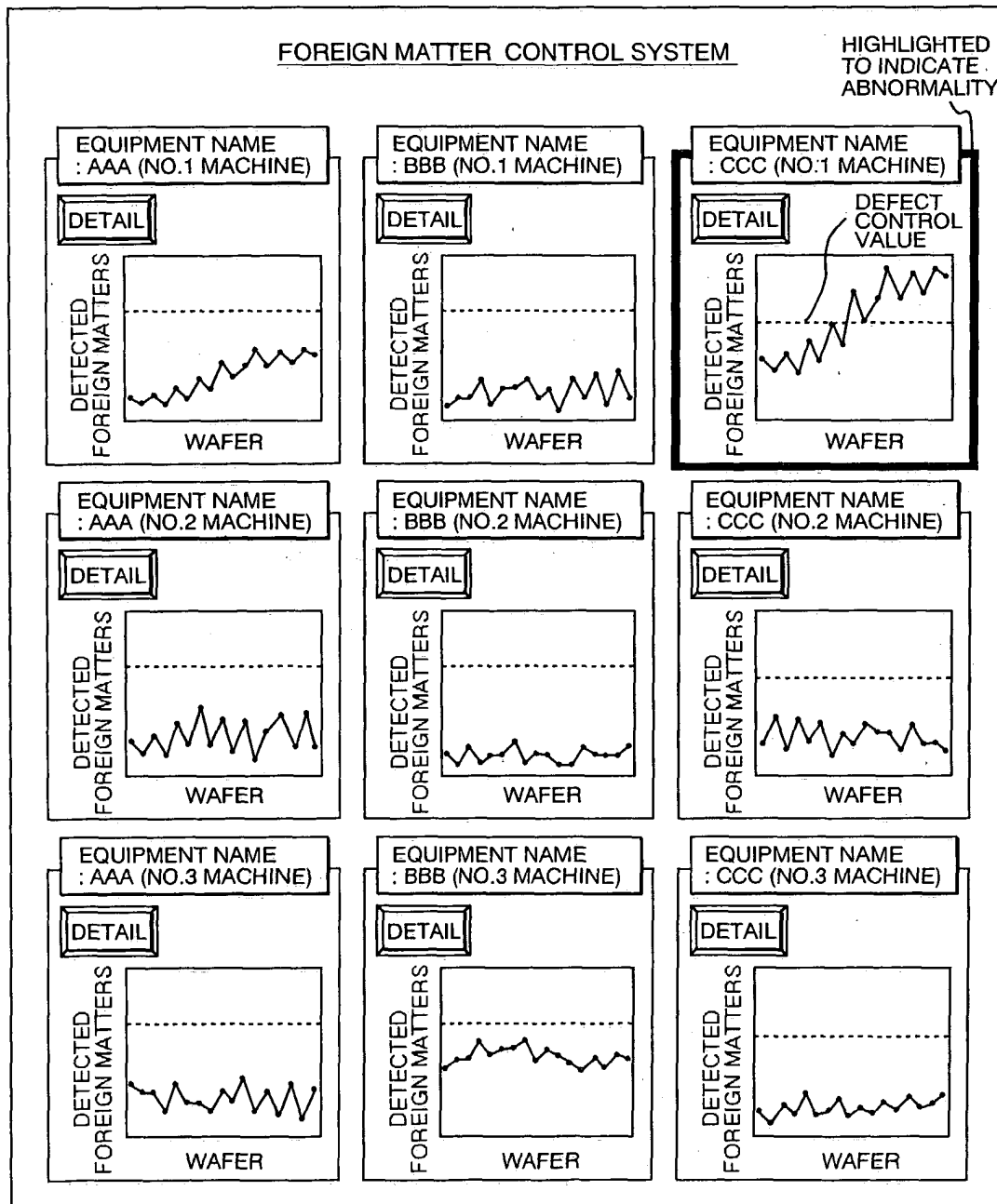
**FIG. 28**

FIG. 29

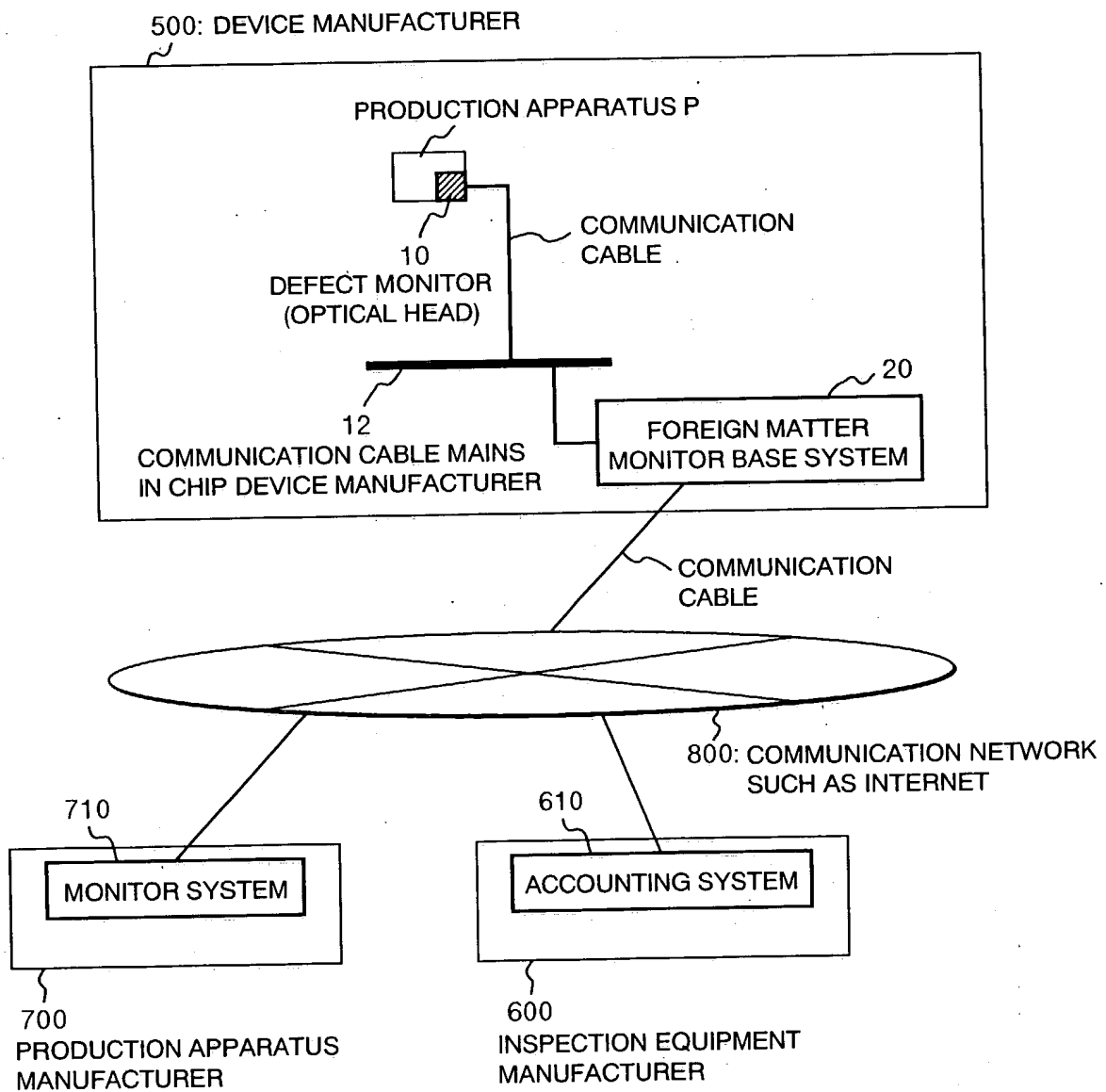


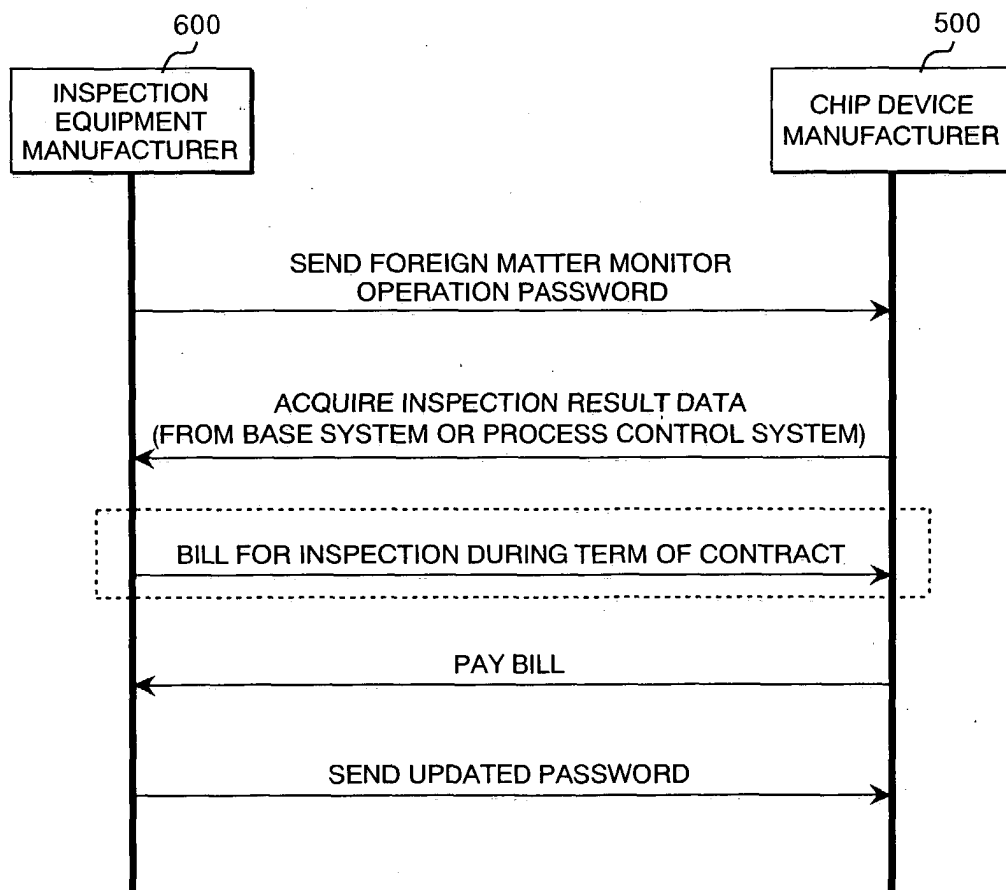
**FIG. 30**

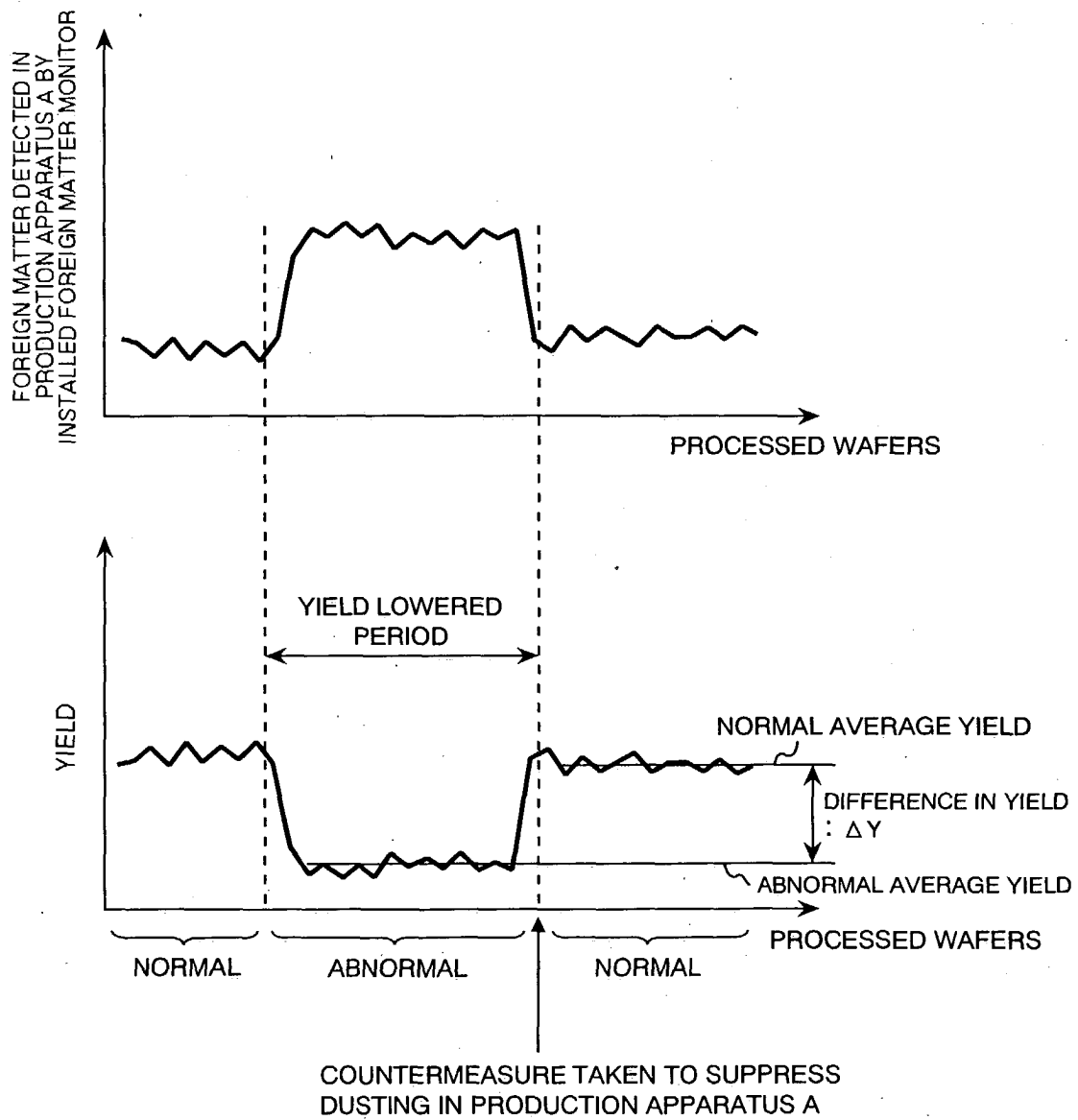


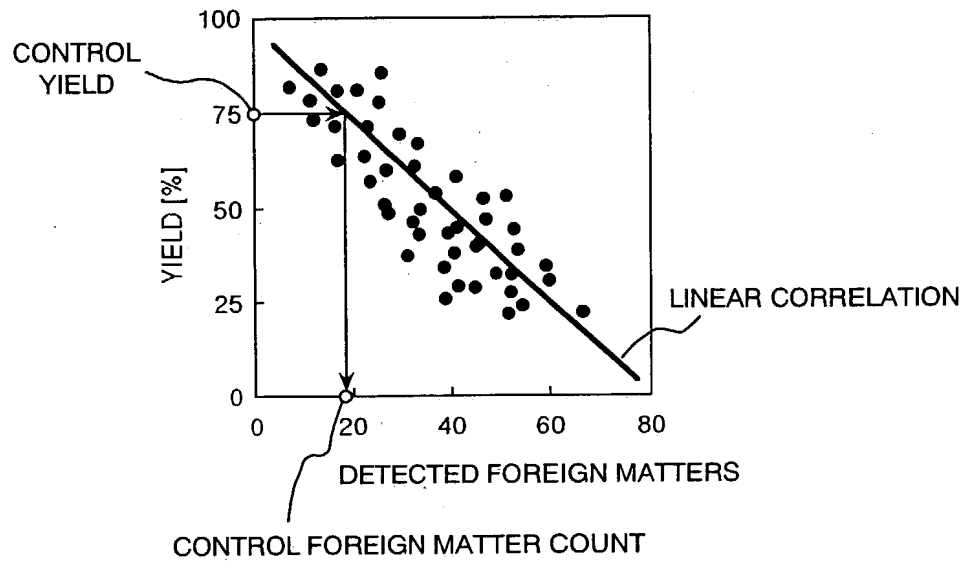
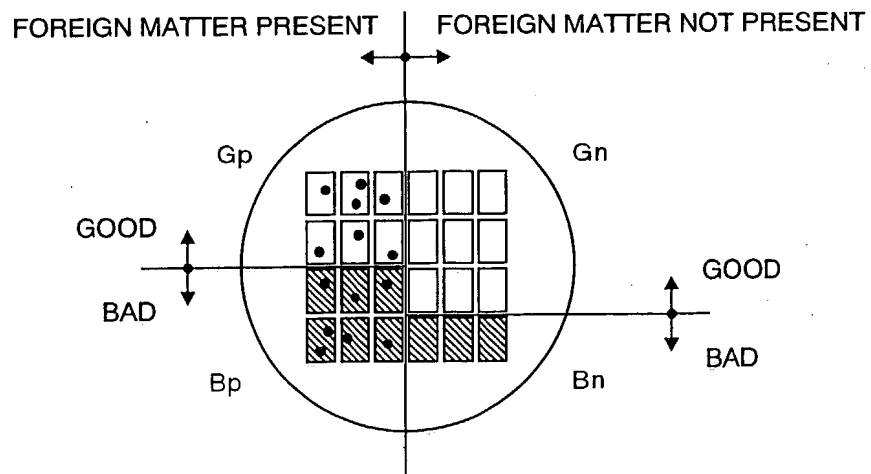
**FIG. 31**

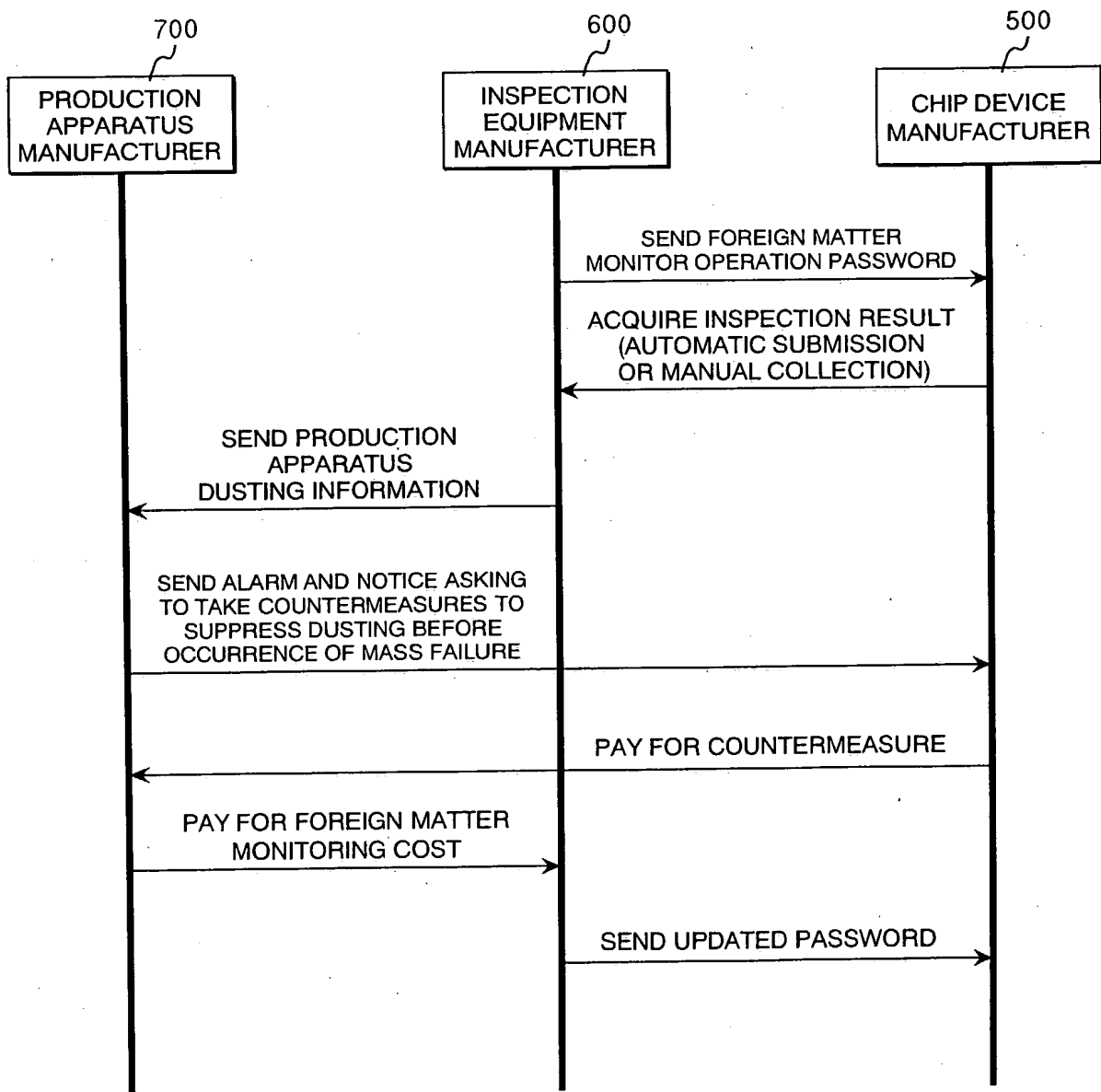
**FIG. 32**

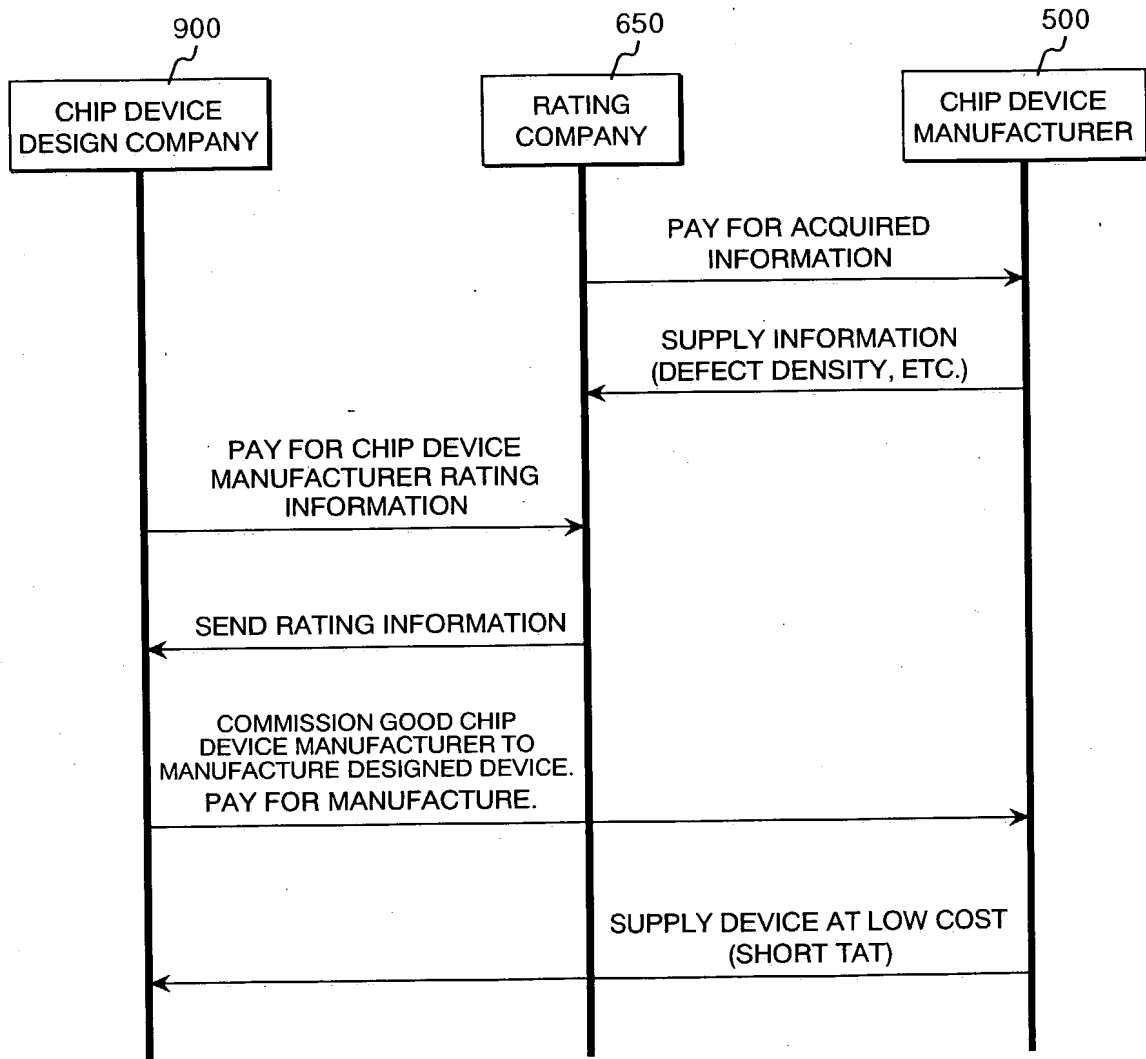


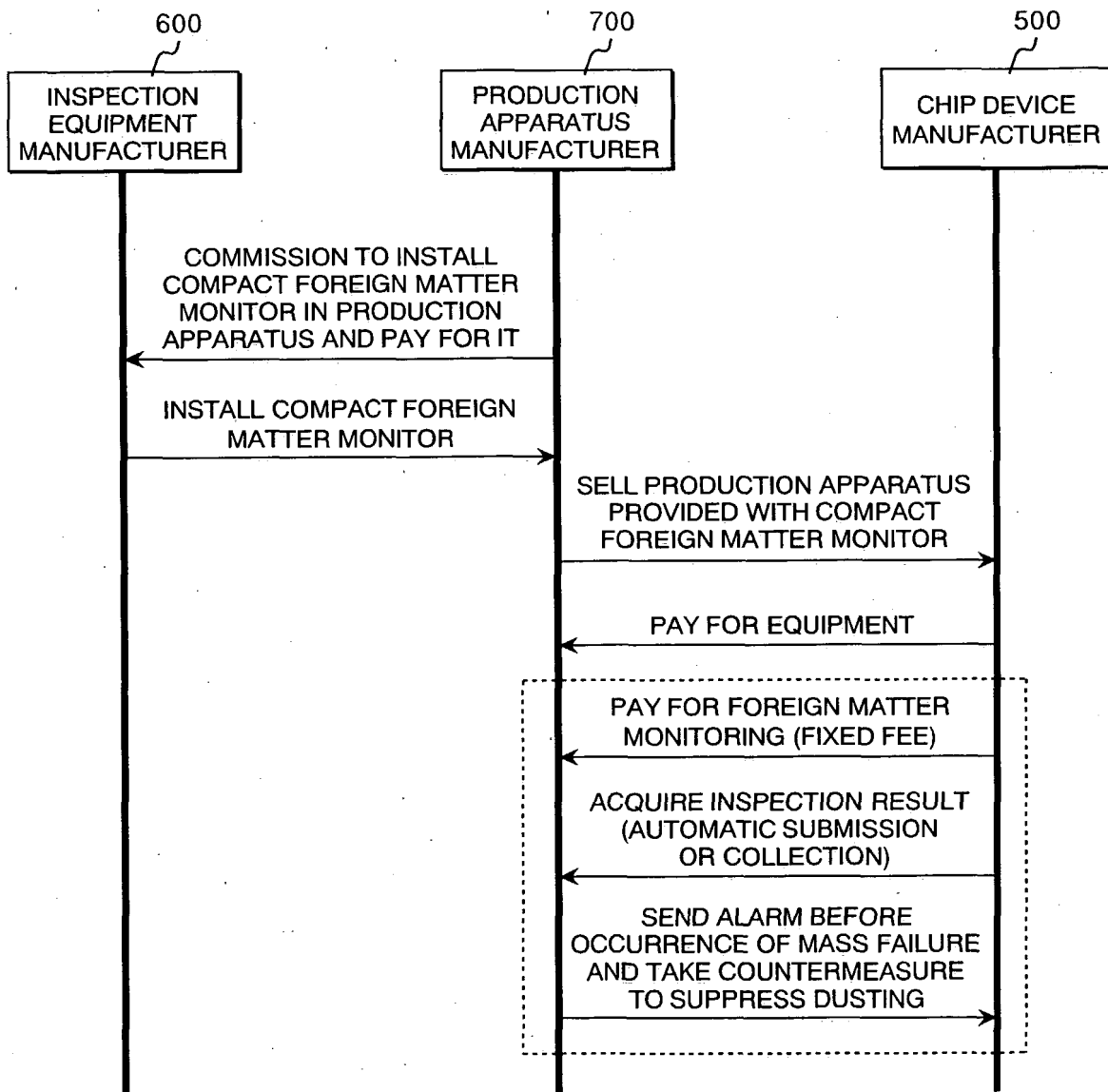
**FIG. 33**

**FIG. 34**

**FIG. 35****FIG. 36**

**FIG. 37**

**FIG. 38**

**FIG. 39**



**FIG. 40**